

The „probe card signature“ – syndrome
or who has the “old maid”

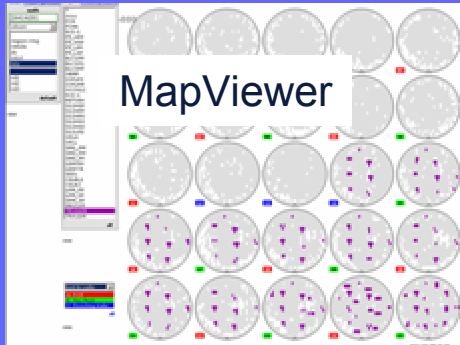
Frank Pietzschmann (IFX)
James Andersen (APLLC)

Dresden,
June 2005



Never stop thinking.

Yield Monitoring Software ...



Data Interface
Yield Report
etc.

Cres online Monitoring



... detect WT yield drops < 1%

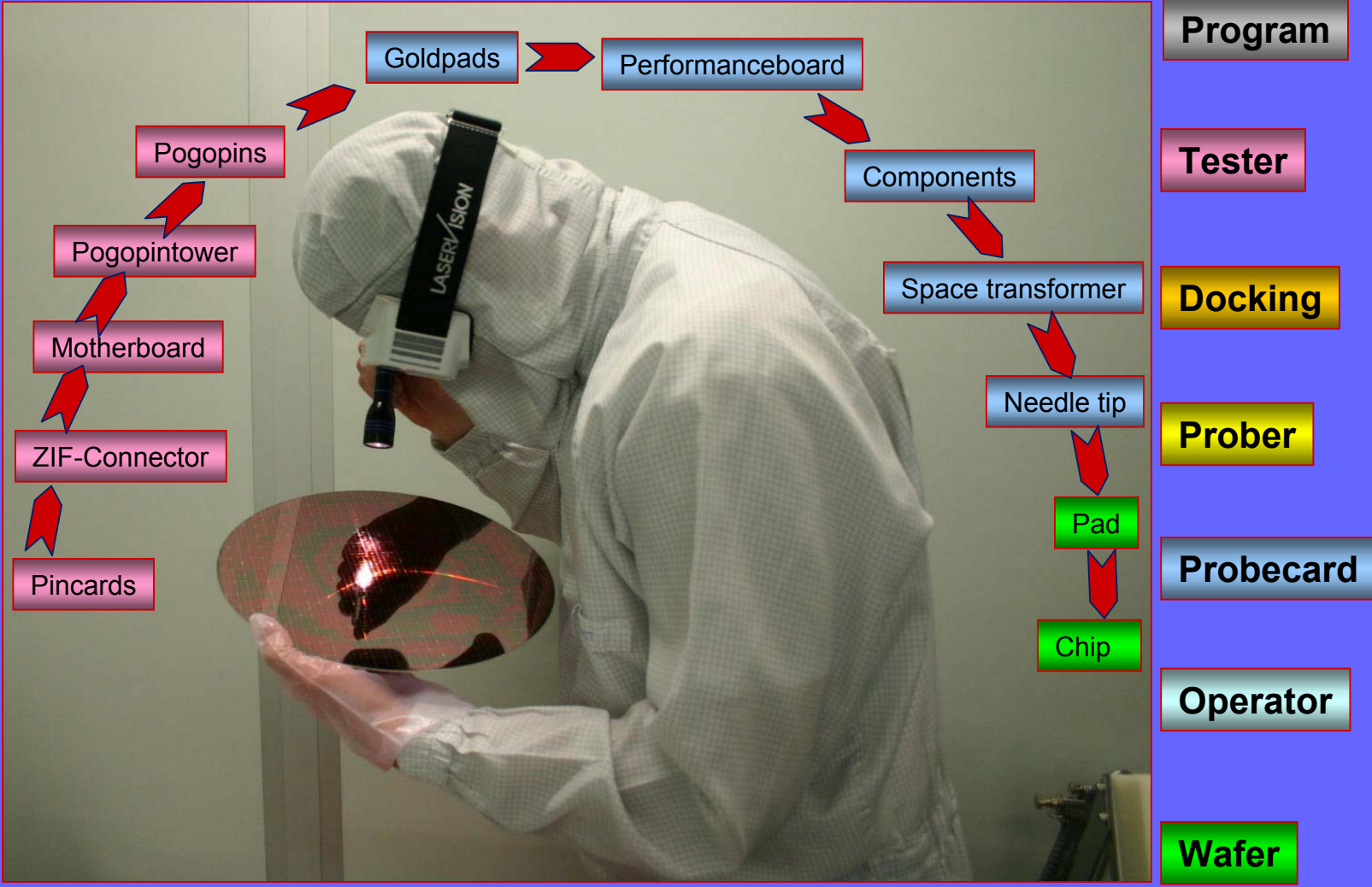
How to find the root cause fast?



1st & only guess is always probe card
and start a cleaning!

But... there are more than 20 different reasons!

The „probe card signature“ – syndrome or who has the “old maid”



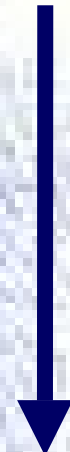
Each WT Failure (yield loss) Has a Unique Root Cause Signature

The „probe card signature“ – syndrome or who has the “old maid”

1. Fixed DUT pattern

2. Statistical pattern

3. Whole wafer w/o pattern



@ preferred wafer regions
@ preferred touchdowns
@ preferred DUT's

Focus on:

the most difficult section

Goal:

rapid root cause analysis

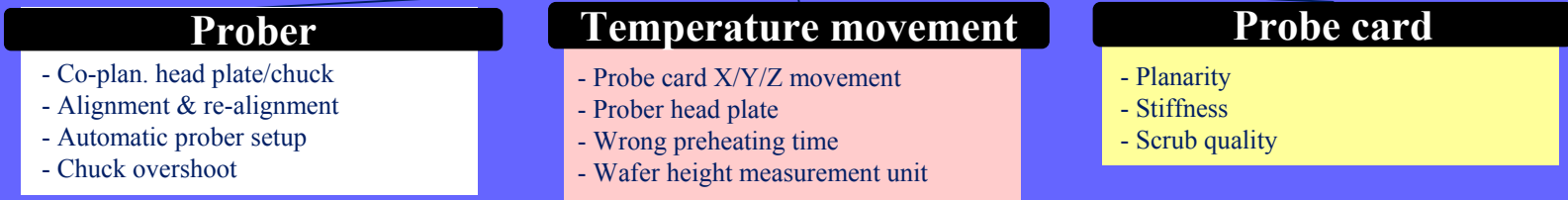


“There is a correlation between the performance and the scrub quality”

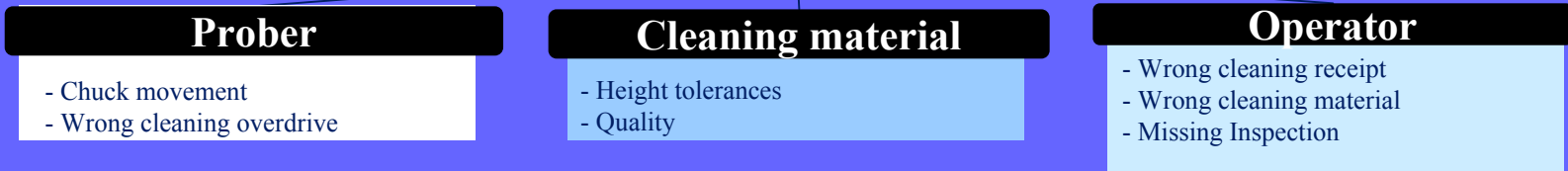
Advanced Analysis Tool

The „probe card signature“ – syndrome or who has the “old maid”

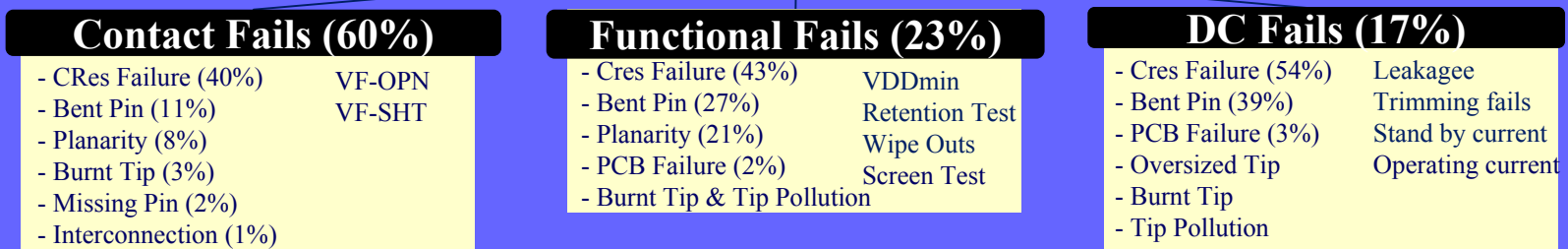
most important → **Overdrive related yield losses**



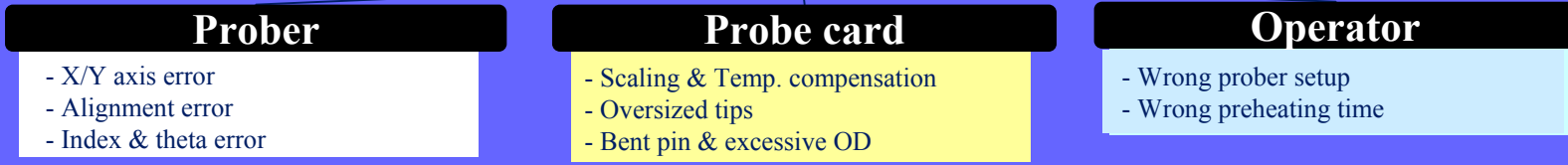
Cleaning related yield losses



Probe card related yield losses

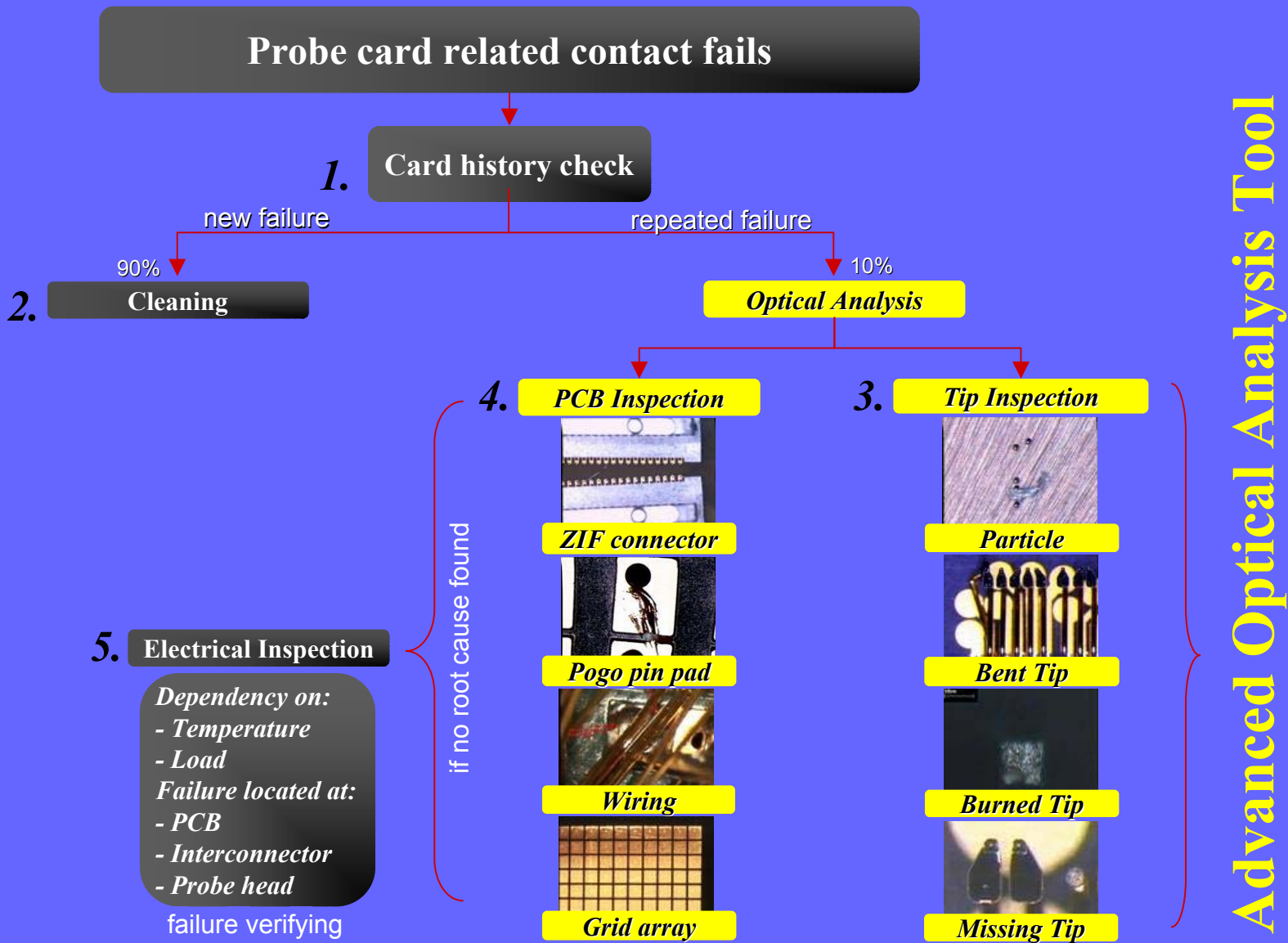


Mechanical related yield losses



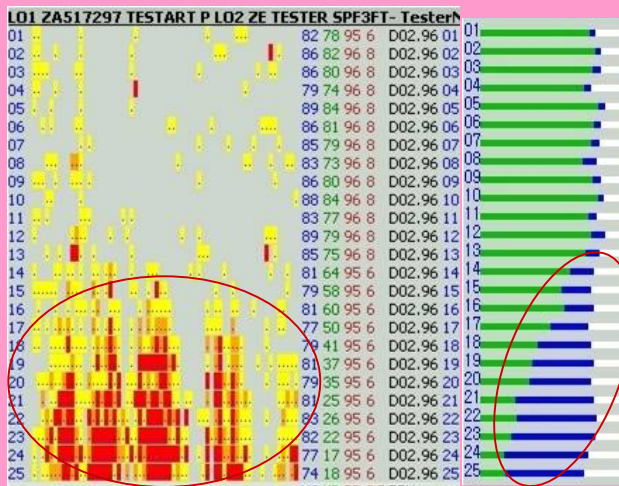
Wafer Test Failure/Yield Loss Classifications

The „probe card signature“ – syndrome or who has the “old maid”



Process Flow Example used to Rapidly Determine Yield-Loss Root Cause Using Advanced Optical Analysis

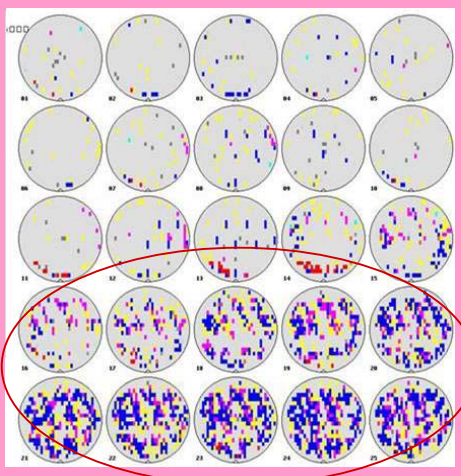
The „probe card signature“ – syndrome or who has the “old maid”



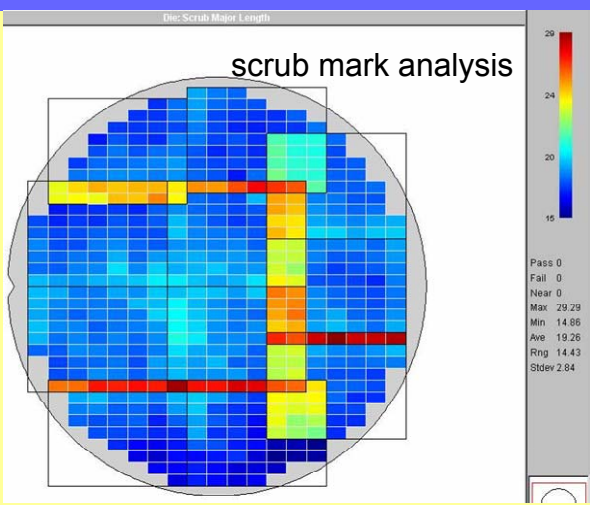
Wafer test tool (Wagner)



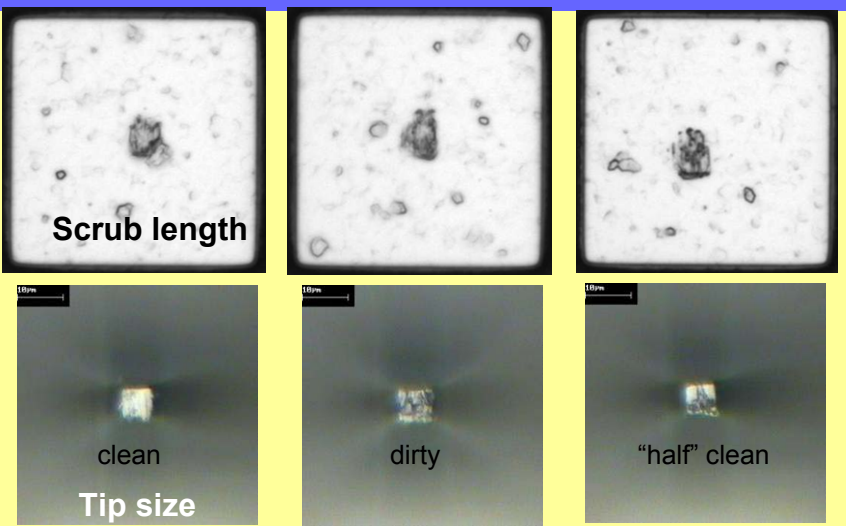
Cres online control



PE map viewer



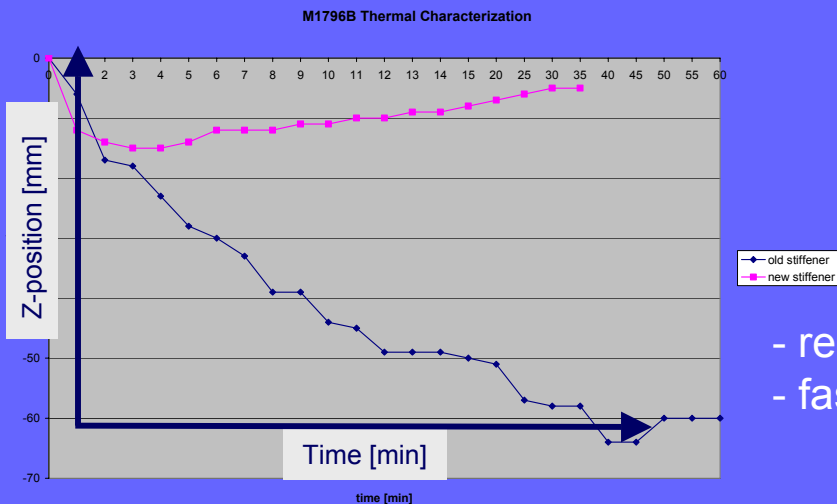
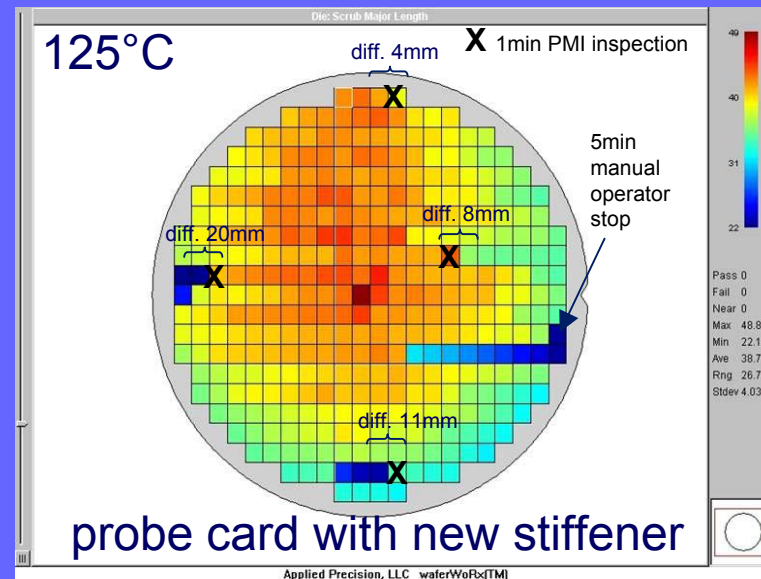
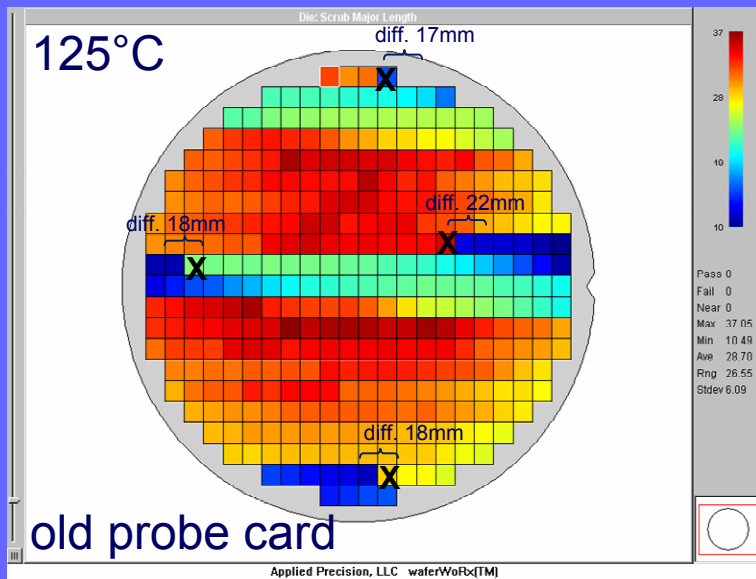
20 30mm OD is missing!



Failure Signature Example – overdrive (prober)

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Comparison Major Scrub Lengths

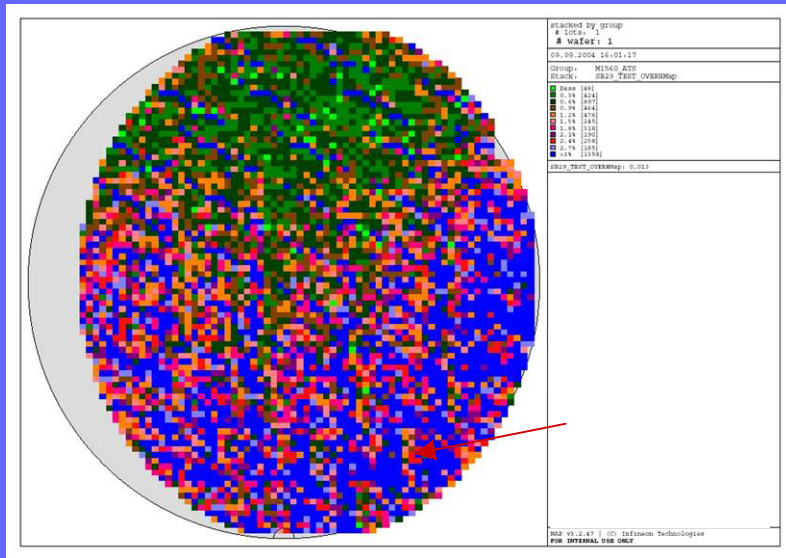


- reduced scrub length
differences $\times 1,6 \dots \times 4,3$
- faster recovery time
up to $\times 3$

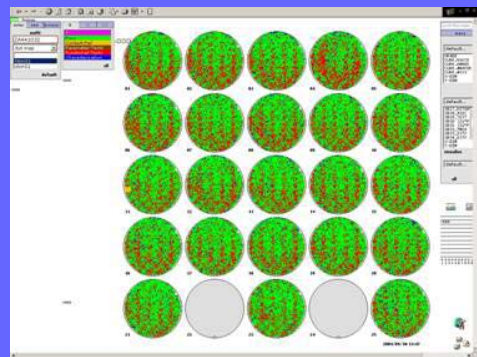
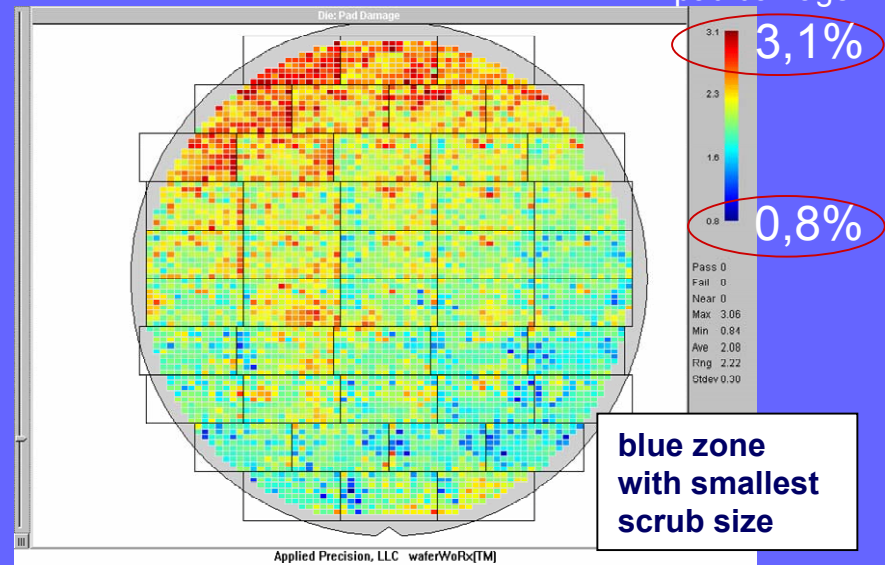
- reduced z-movement range $\times 4,3$
- faster return point $\times 10$

The „probe card signature“ – syndrome or who has the “old maid”

yield stacked map 23 wafers

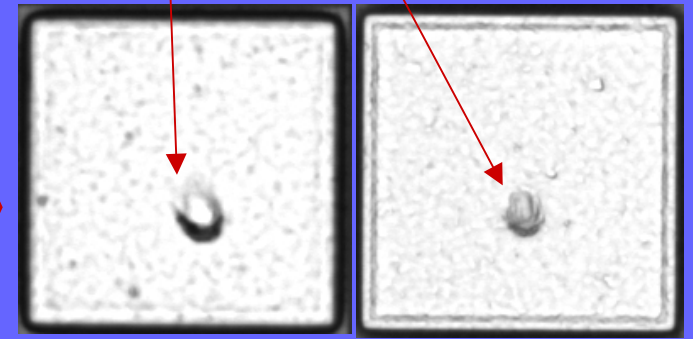


scrub mark analysis 1 wafer



matched pattern!

same pin with different scrub sizes over the wafer!



Failure Signature Example – chuck movement (shift)

The „probe card signature“ – syndrome or who has the “old maid”

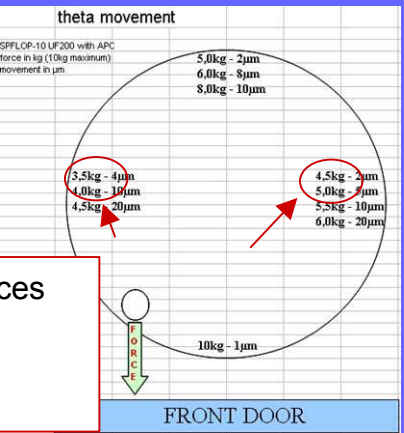
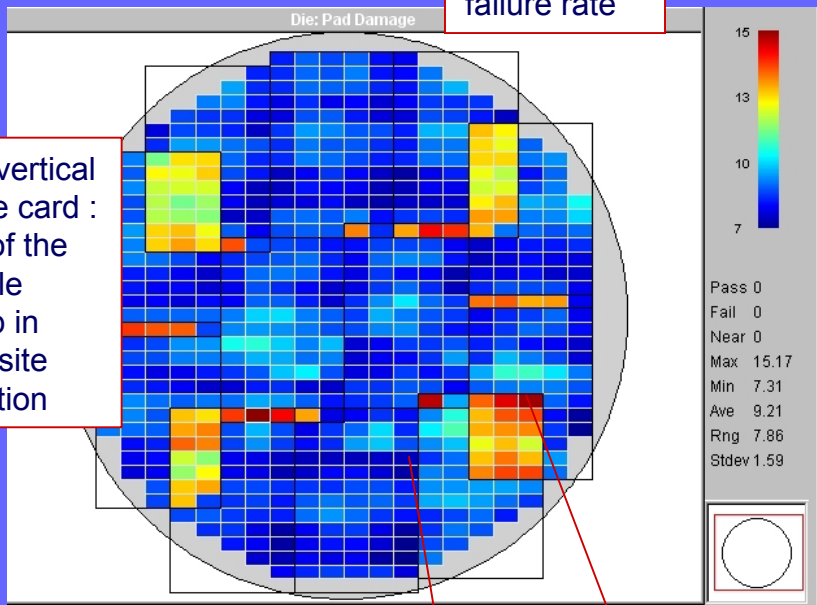
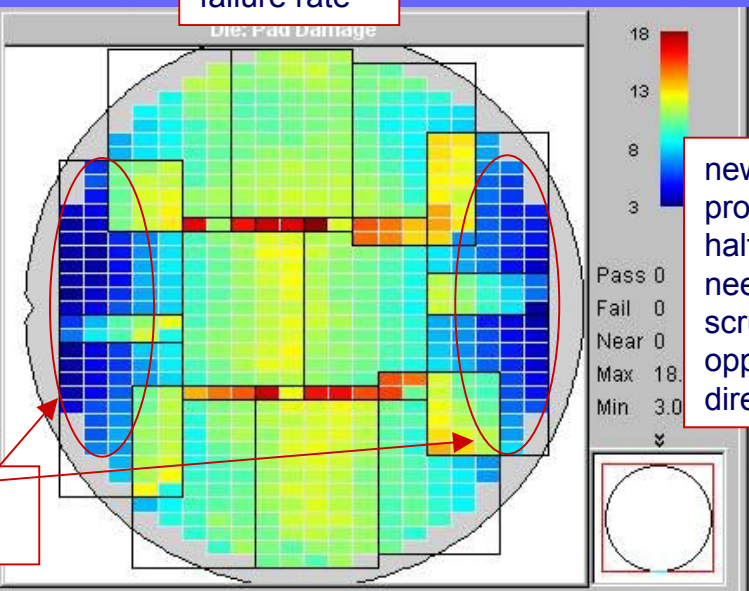
Inconsistent pad damage = higher failure rate

Consistent pad damage = lower failure rate

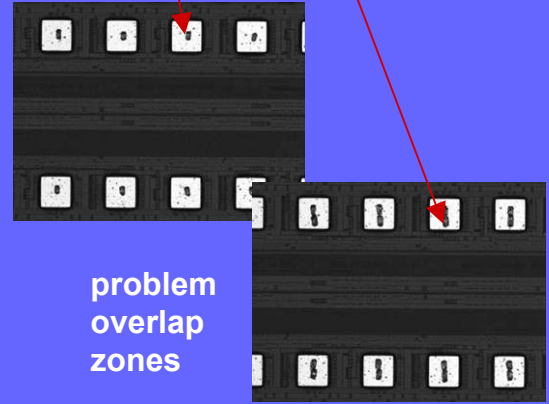
standard vertical probe card : all needles scrub in one direction

new vertical probe card : half of the needle scrub in opposite direction

highest failure rate



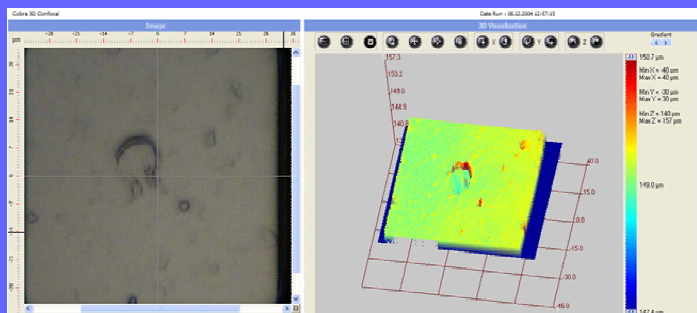
This movement reduces the scrub length = online cleaning necessary



problem overlap zones

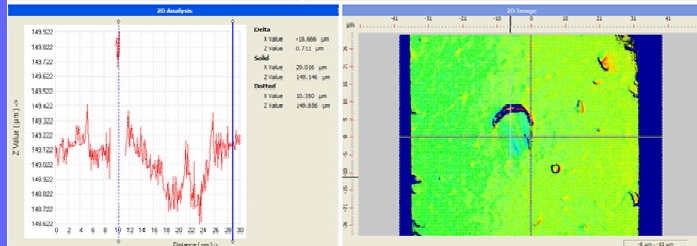
Failure Signature Example – chuck movement (theta)

The „probe card signature“ – syndrome or who has the “old maid”

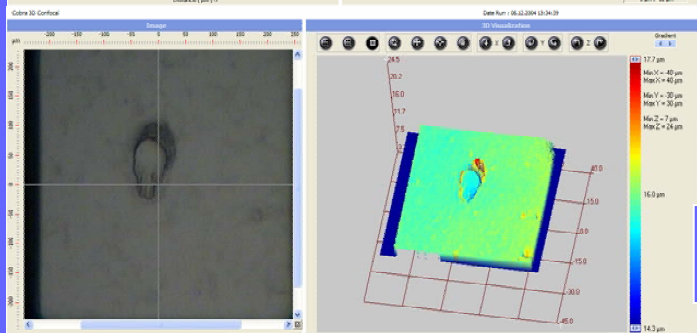


Chip 03/08
DUT 49, Pin 25

Scrub heel = 547 nm
Scrub valleys = 492 nm*)

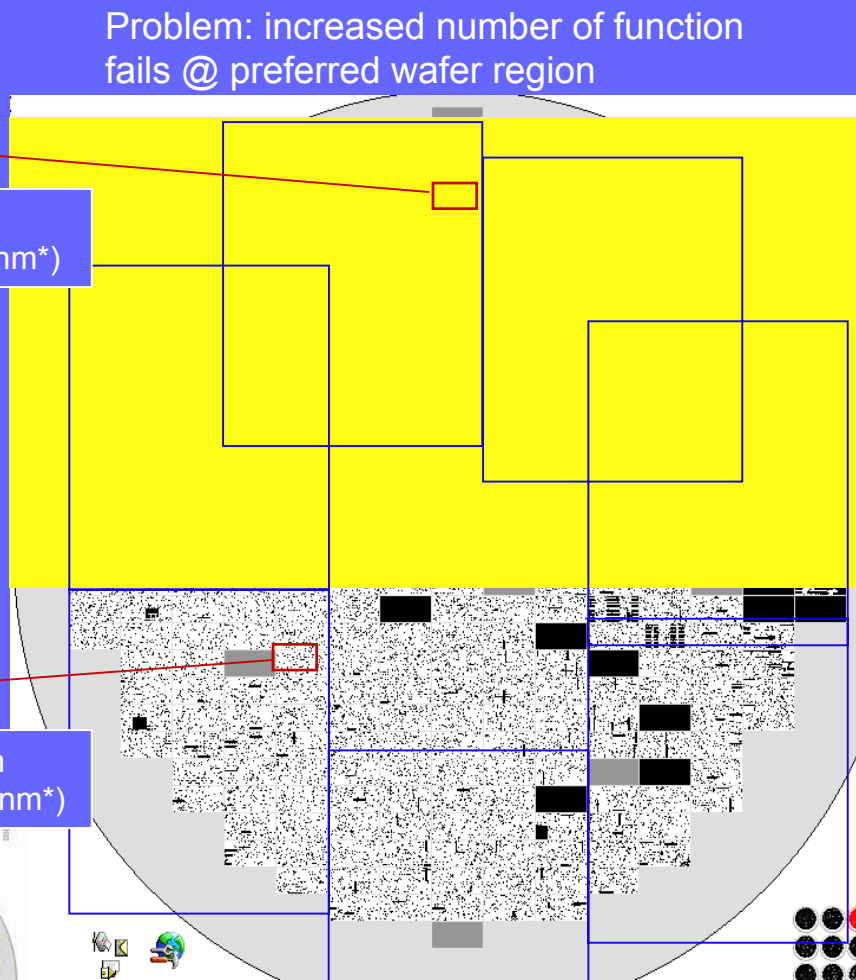
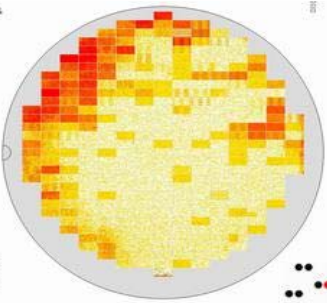
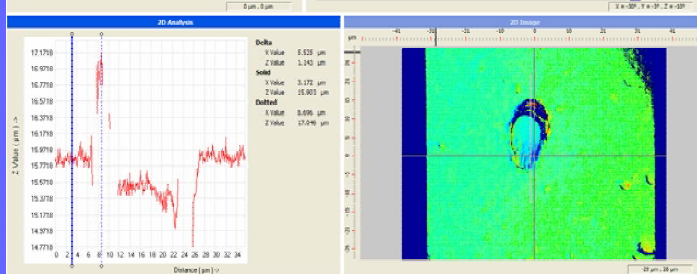


scrub height
-675nm
penetration depth
-583nm



Chip 20/05
DUT 49, Pin 25

Scrub heel = 1285 nm
Scrub valleys = 1075 nm*)



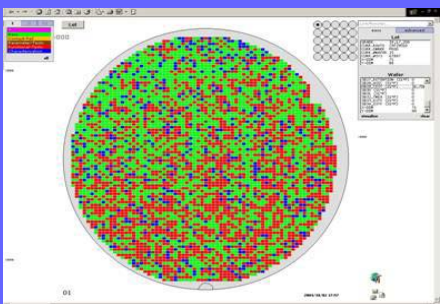
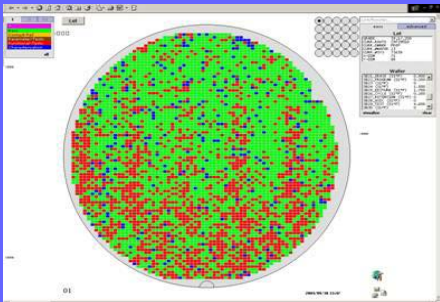
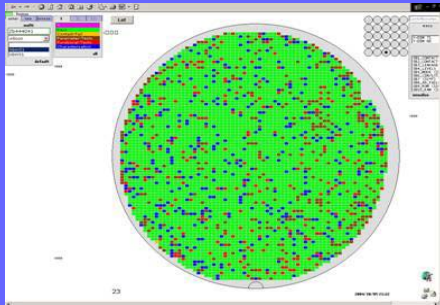
Problem: increased number of function fails @ preferred wafer region

yield stack map

*) ave. number of measurements/ pins: 12/6

The „probe card signature“ – syndrome or who has the “old maid”

SB29 fails



optical tip inspections

level 1: <2,5%
new or clean probe tips



level 2: “moon signature”
normal tip stage after 3 weeks w/o
cleaning

level 3: >5...30%
random distribution
tips contaminated: “black
dots” visible



Must Clean On-line More Often

Root Cause Analysis Contact Problems

“First thing to obtain a good test is the good contact... It’s unbelievable how much time production spends on this point. Therefore it’s possible to improve the contacts in electrical way, which is in the hands of test engineer”

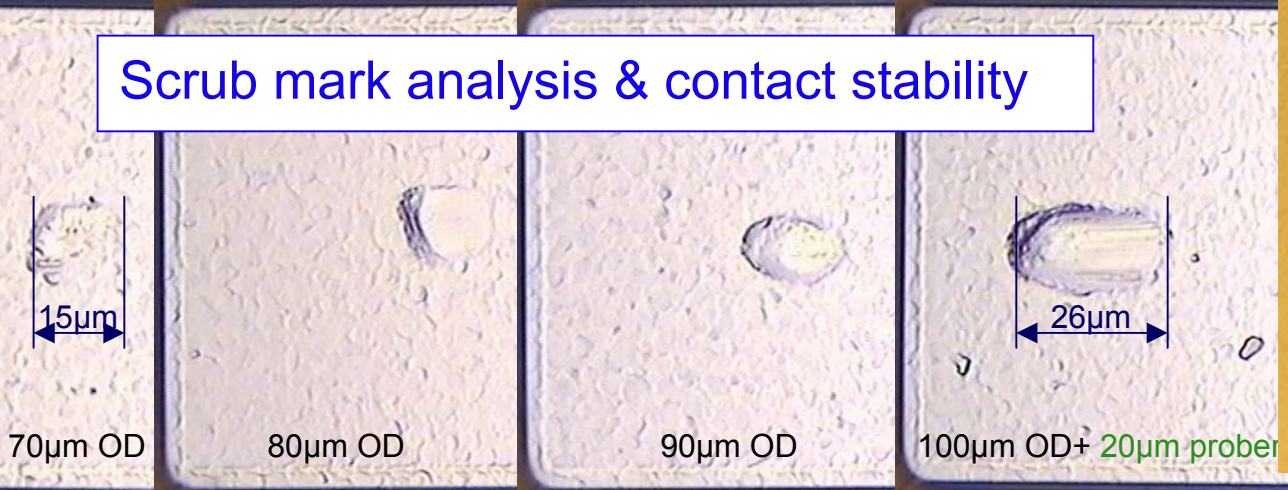


burned beam

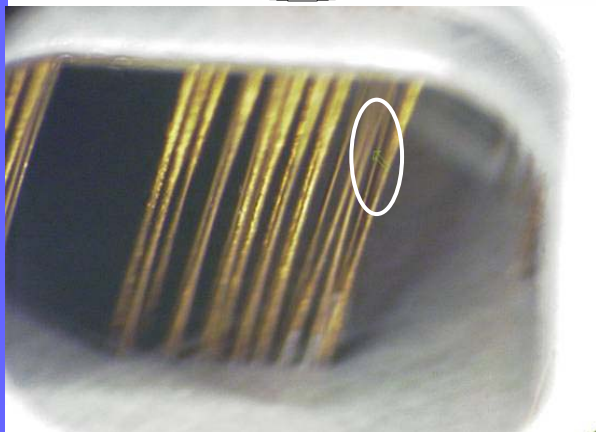
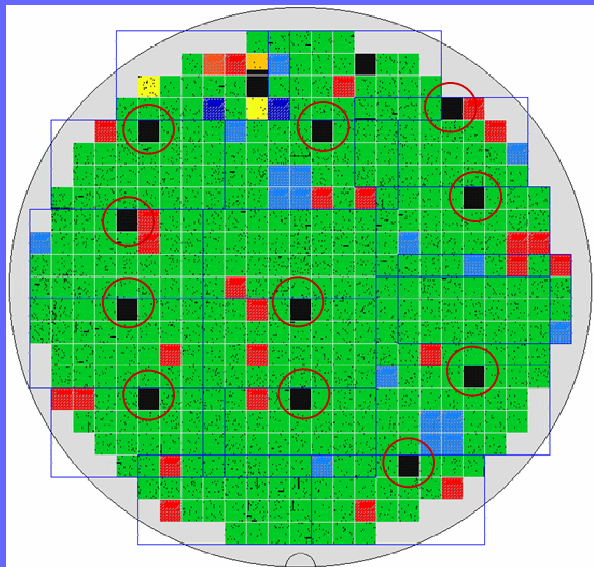


Implemented test:
Test forces -5mA pin-by-pin at every BPMU card. The forcing voltage can reach -24V. Number of simultaneously forced pins is equal to BPMU cards attached to device. On contact problem first the Al2O3 is electrically broken, than small current is forced to clean the contact and decrease the contact resistance.
! IMPORTANT ! GND and all supply voltages must be forced to 0V.

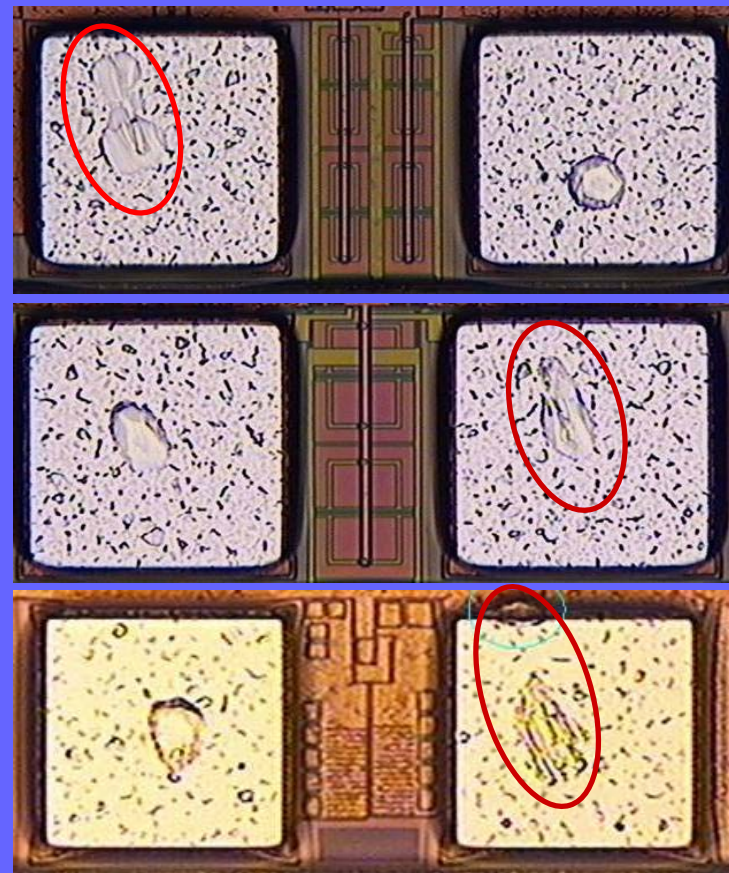
Scrub mark analysis & contact stability



The „probe card signature“ – syndrome or who has the “old maid”



TSLY Wipeouts at
VDDmin on one
DUT

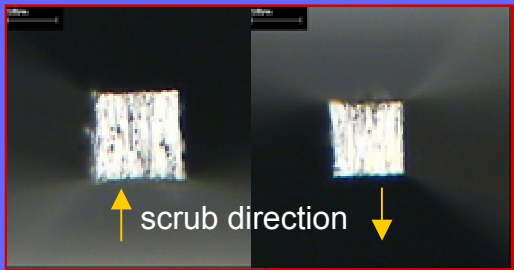


scrub shape changes
due to burning

neighboring VDD,GND-beams sticks on each other
root cause: current clamp value not valid during bump
test = 400mA/20s

Failure Signature Example – VDD/GND Burning

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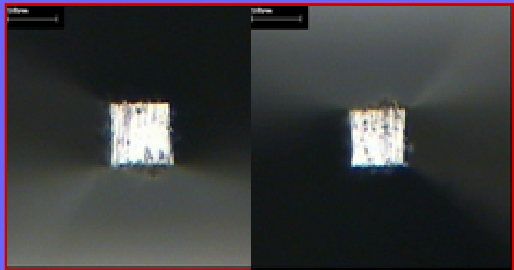


tip size max. 17mm

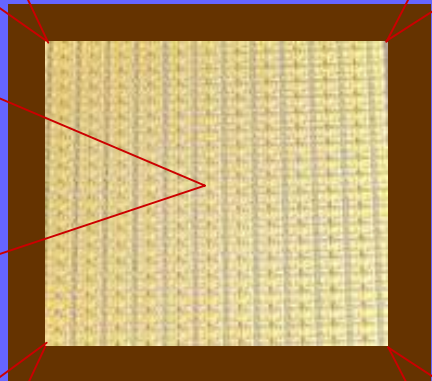
non uniform tip size increasing over the time
dependency on:
- scrub direction
- probe array location



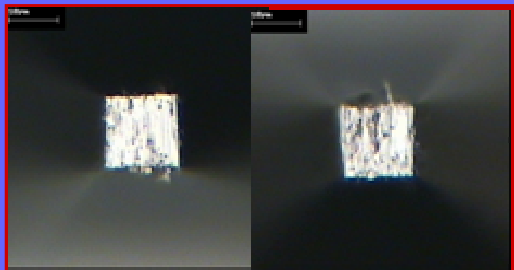
tip size max. 19mm
end of live 22mm



tip size max. 11mm

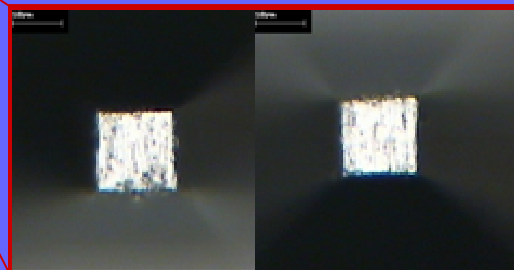


after one year &
22 abrasive cleanings



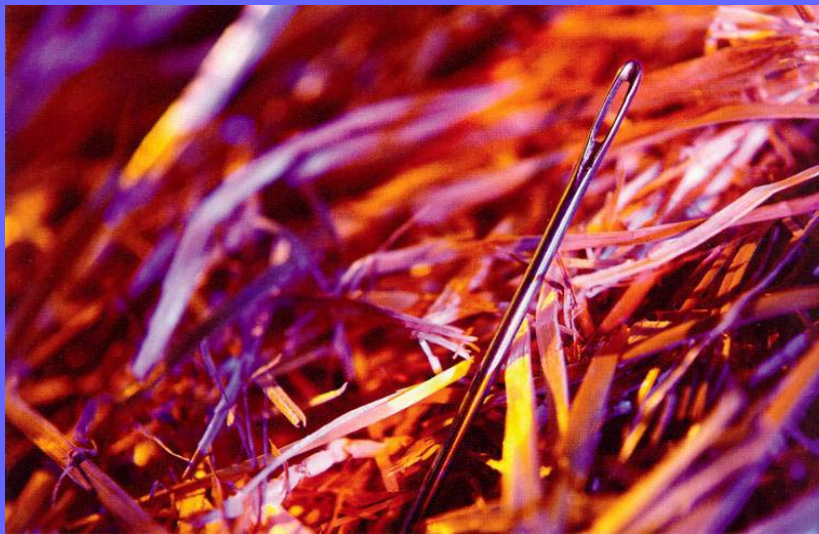
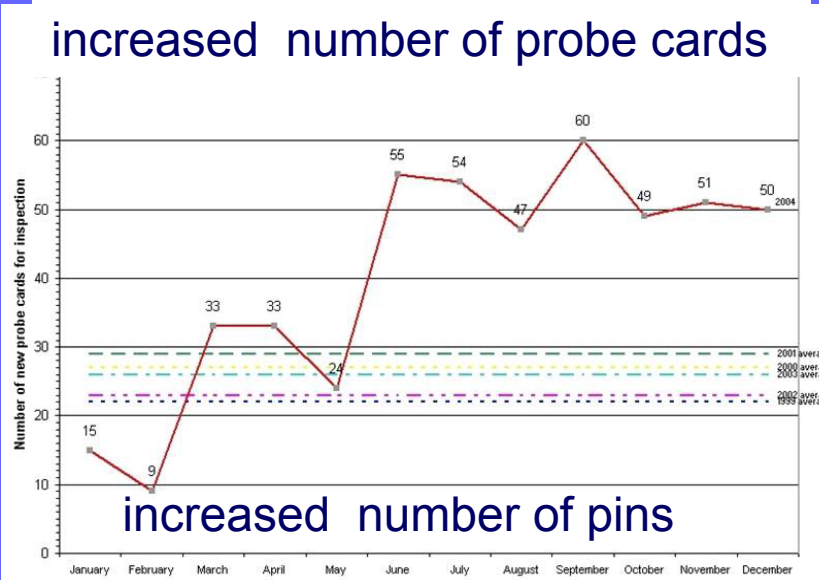
tip size max. 14mm

early detection of burning, wear, quality issues can reduce repair cost >50.000 €/year



tip size max. 14mm

Mechanical Related Yield Loss Example - Tip Size Alert



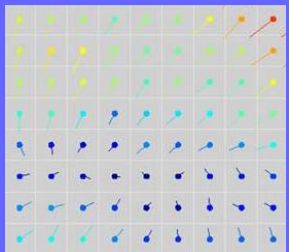
Advanced Optical Analysis Tool
scrub mark analysis enhances incoming inspection



The „probe card signature“ – syndrome or who has the “old maid”



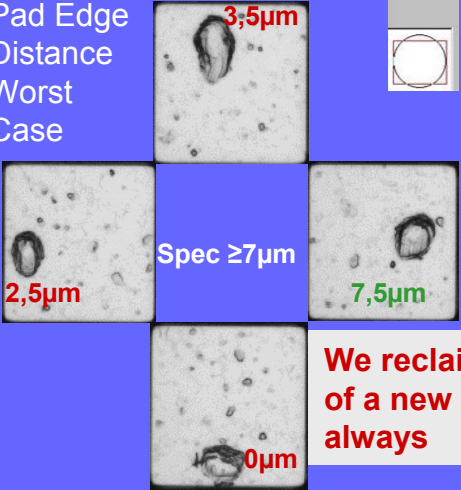
Scrub X/Y-Position Error
– Ave. per die



Pass 0
Fail 0
Near 0
Max 19.47
Min 0.00
Ave 10.95
Rng 19.47
Stdev 4.99

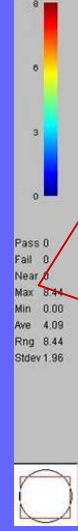
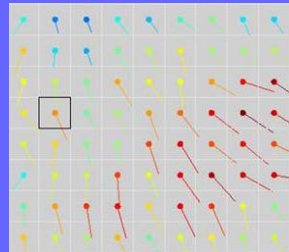
max. 19,5mm
ave. 10,9mm
stdev. 5mm

Pad Edge
Distance
Worst
Case



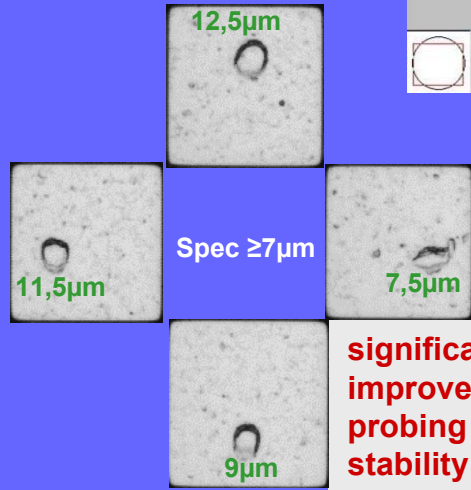
**We reclaimed the first cards
of a new technology step
always**

Scrub X/Y-Position Error
– Ave. per die



Pass 0
Fail 0
Near 0
Max 8.44
Min 0.00
Ave 4.09
Rng 8.44
Stdev 1.96

max. 8,4mm
ave. 4,0mm
stdev. 1,9mm



**significant
improvement for
probing process
stability**

The „probe card signature“ – syndrome or who has the “old maid”

(1) Z movement probe array

range: up to 110um
time: over 2h preheating
direction: -Z or/and +Z

(2) X & Y material expansion

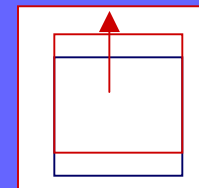
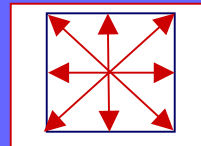
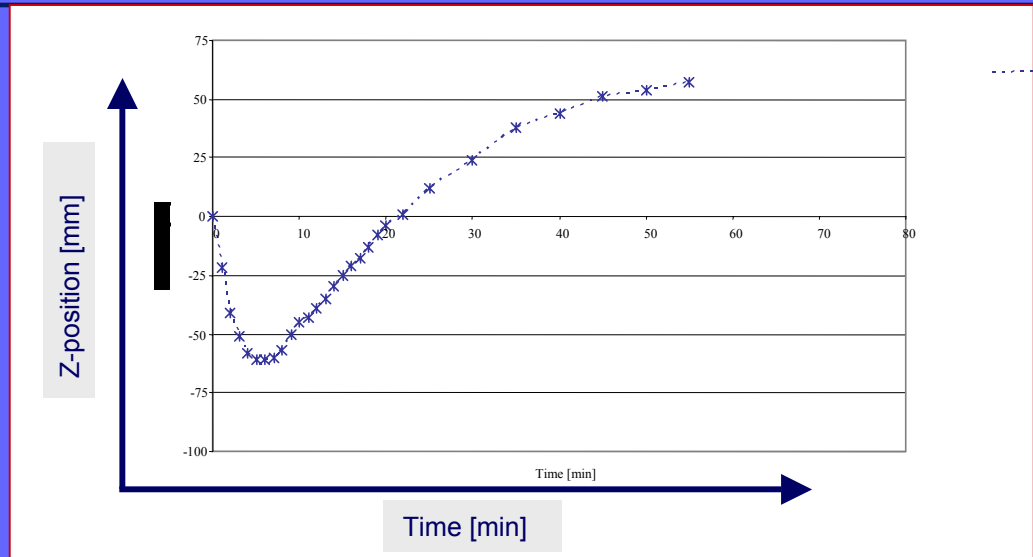
range: up to 15um / 150mm
time: < 20min of preheating
direction: star like

(3) X or Y drift probe array

range: up to 35um
time: over 5h preheating
direction: X or Y

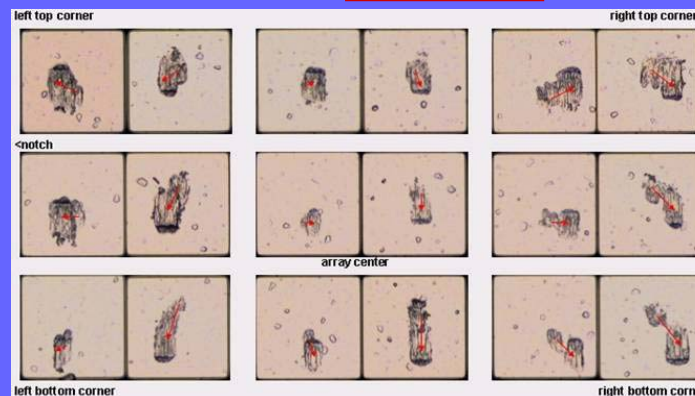
(4) Single needle movement

range: 3...15um
time: 1st h of preheating
direction: each needle different



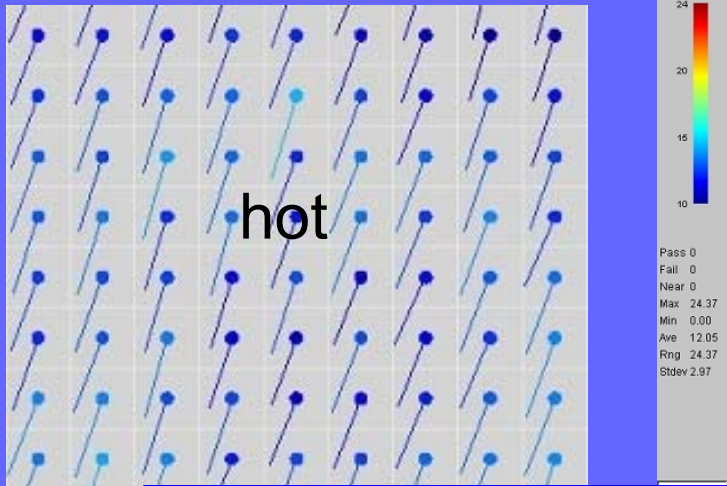
dependency on:

- probe card construction
- used stiffener material
- PCB properties

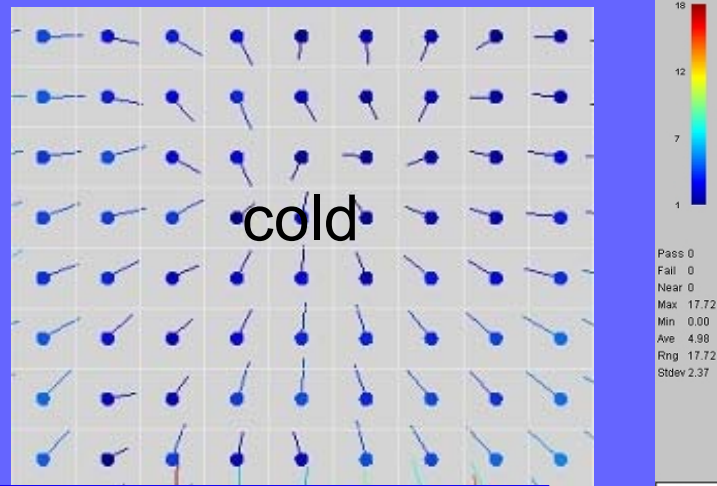


The „probe card signature“ – syndrome or who has the “old maid”

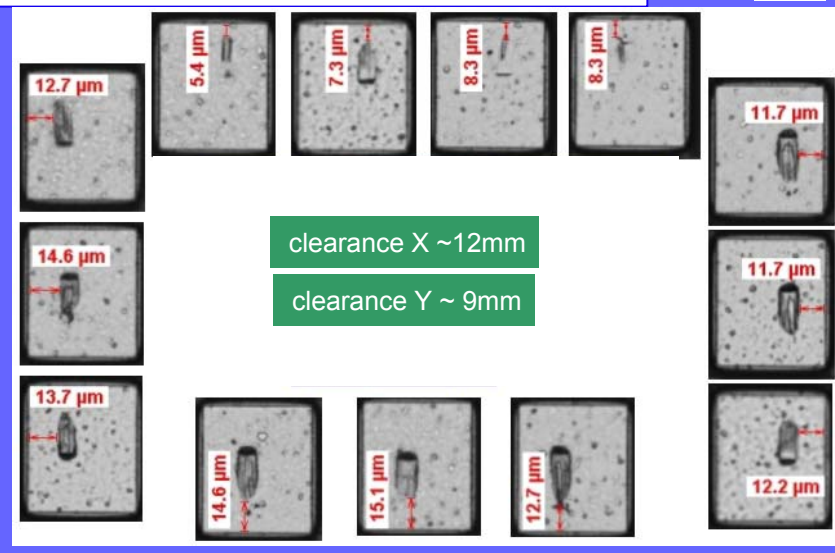
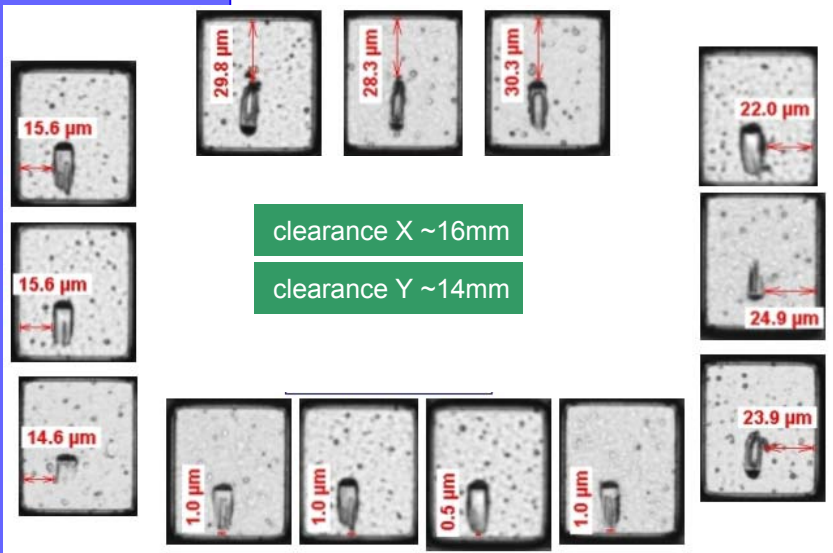
Scrub X/Y-Position Error



Scrub X/Y-Position Error

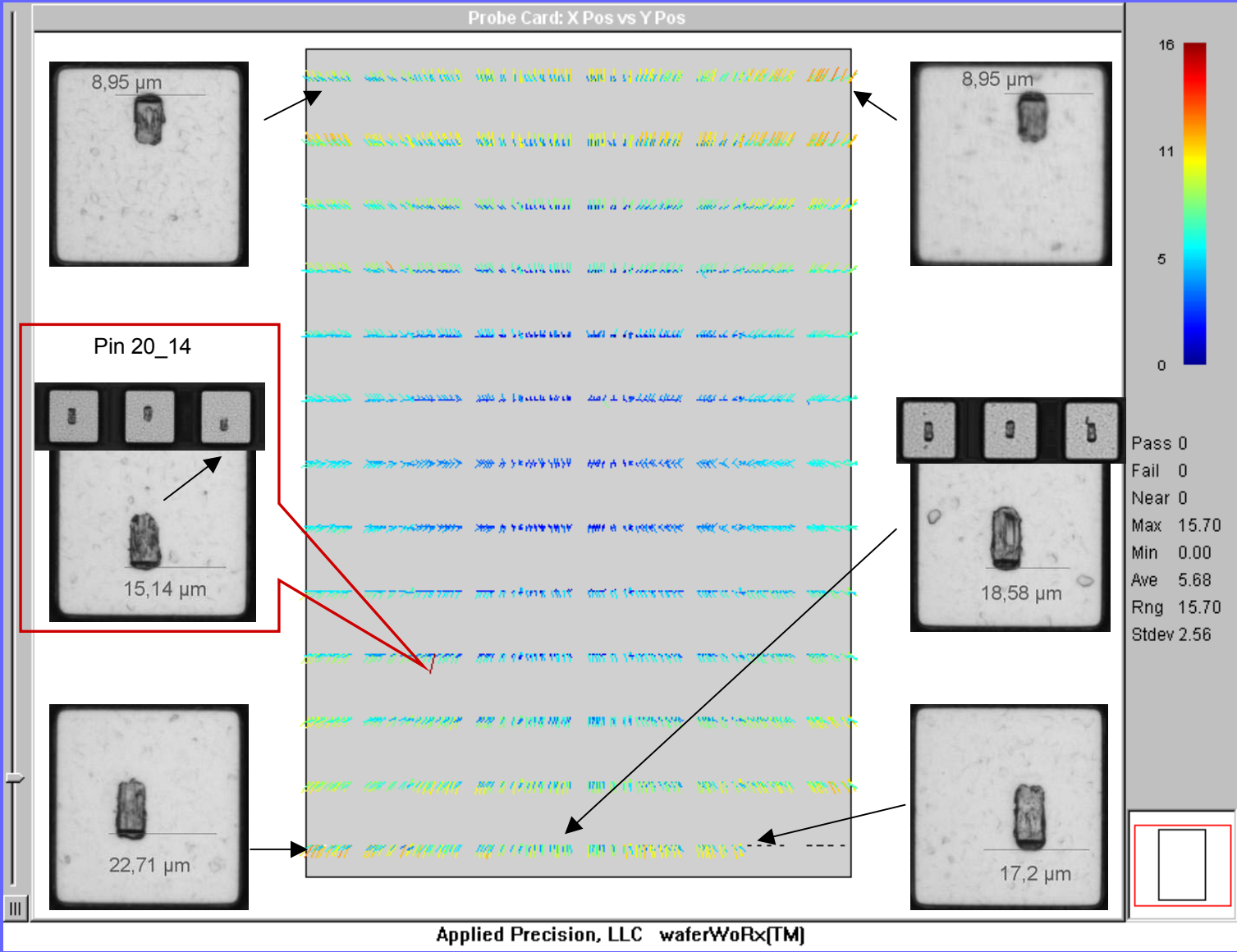


PC-Manufacturer measure the probe card @ room temperature

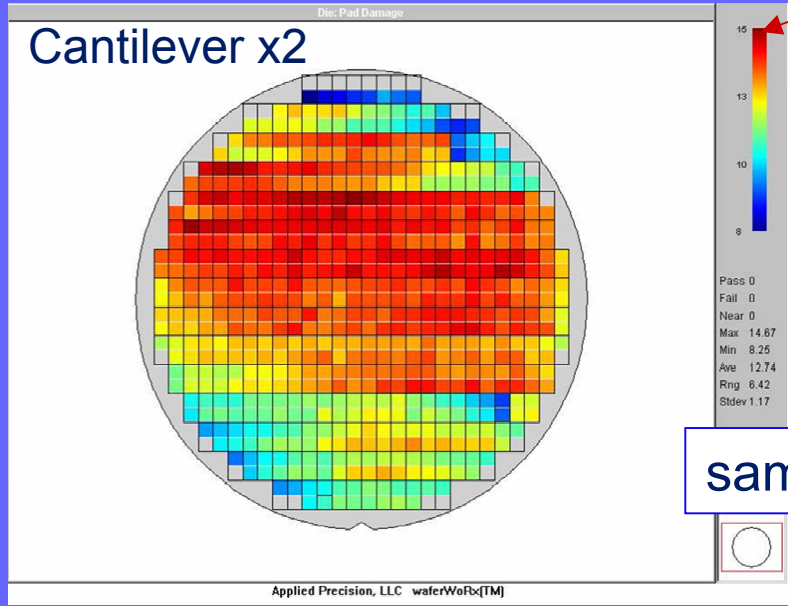


Advanced Optical Analysis - Offset/scaling @ temp Assessment

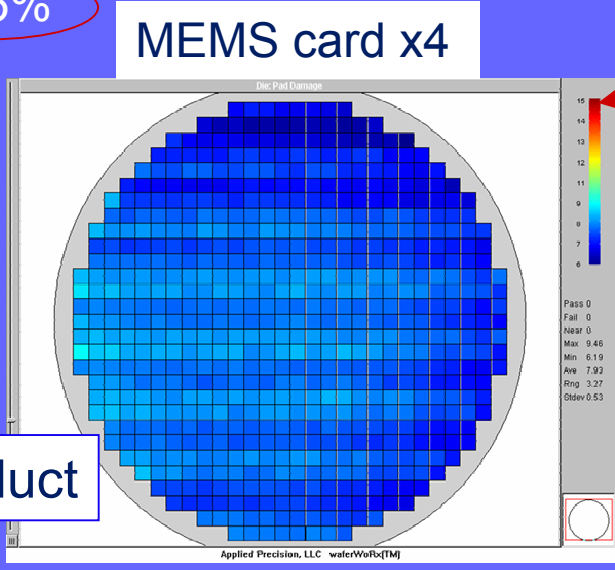
The „probe card signature“ – syndrome or who has the “old maid”



The „probe card signature“ – syndrome or who has the “old maid”



15%



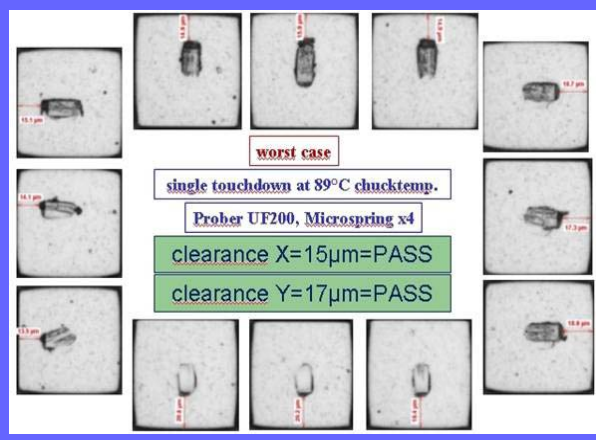
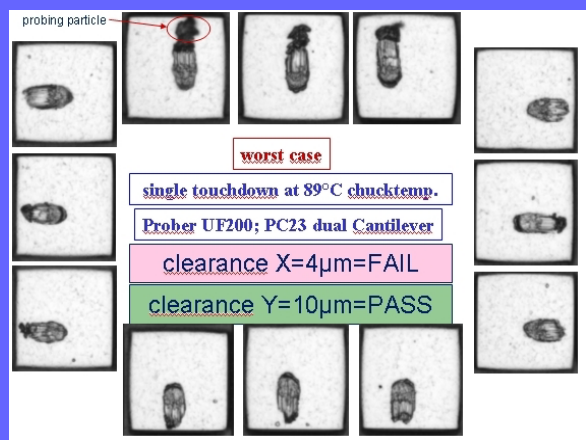
pad damage

15%

same product

reduced pad damage -5%

worst case
distance
scrub end to
pad edge

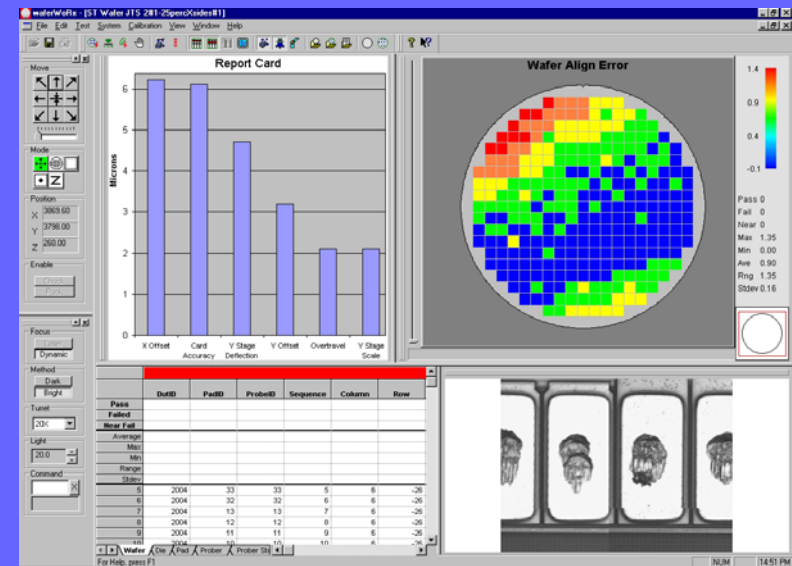
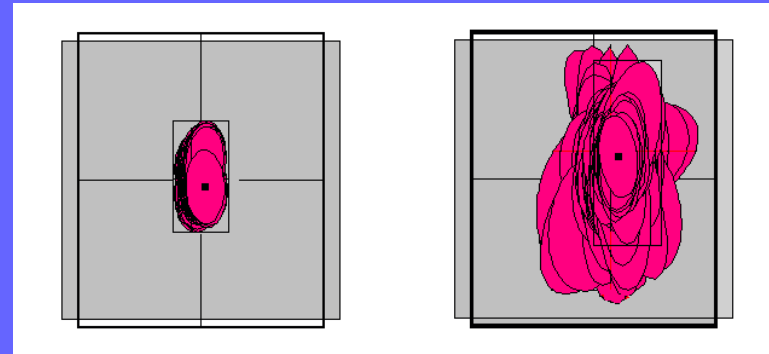


What Metrology Tool Capabilities are Required to Bridge the Gaps Between Yield Monitoring SW & Root Cause Analysis?

- **Automated 300mm Probing Process (Scrub Mark) Data Collection and Analysis (2D and 3D)**
- **Automated 3D Probe Tip Data Collection, Review, & Analysis**
- **Exposed Oxide/Pad Punch-Thru Detection**
- **Closed Loop Metrology Enabled**

300mm/200mm/150mm Probing Process (Scrub Mark) Data Collection and Analysis

- Define Wafer Test Process Tolerance and Precision
- Identify Probing Process Issues Via Wafer Scrub Mark Analysis
- Quantify the Contribution of Wafer Test Cell Components Based on Scrub Mark Data

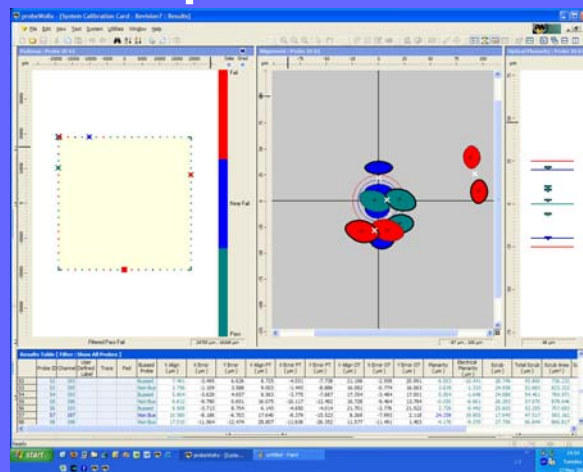


Scrub Marks are the Fingerprints of the Probing Process

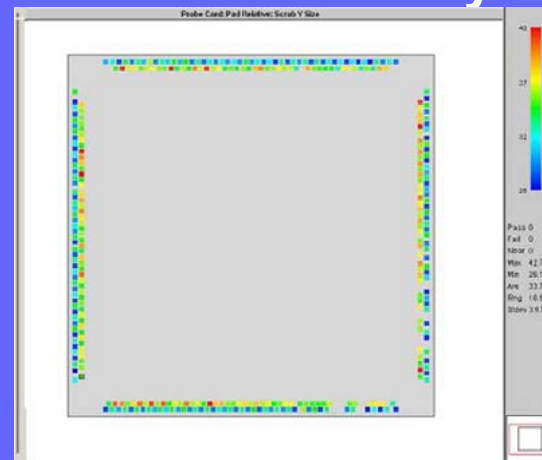
Automated 2D/3D Probe Tip and Scrub Data Collection & Analysis

•Identify Probes & Scrubs of Interest

- Based on PCA P/F results
- Based on Scrub P/F Data



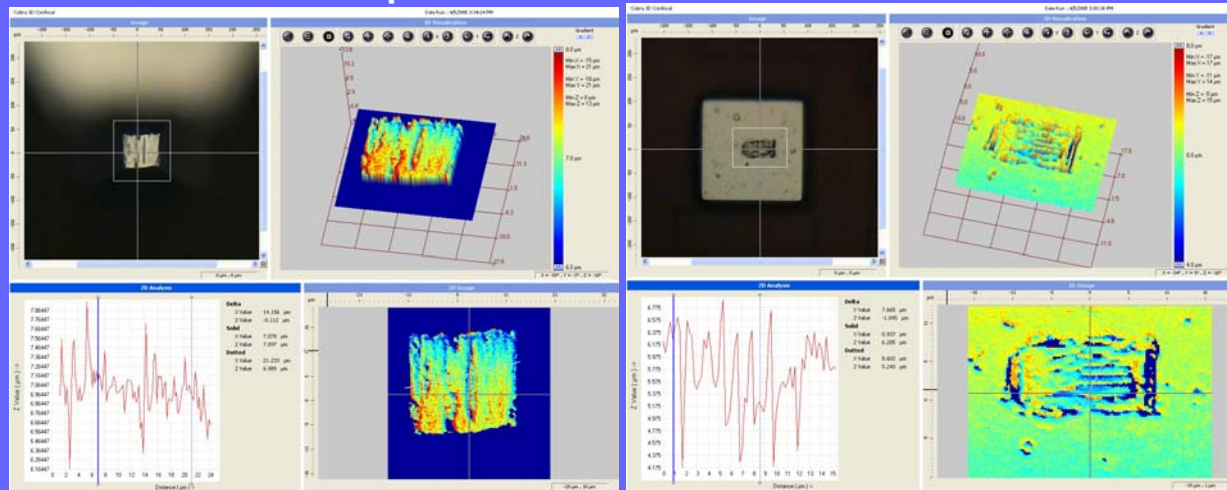
Probe Card/Tip Data



Probing Process Data

•Rapidly:

- Locate
- Review
- Analyze
- Rework Probes



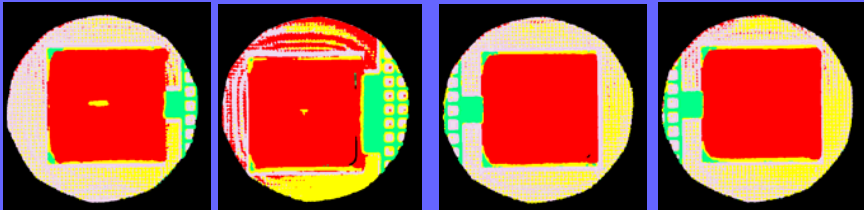
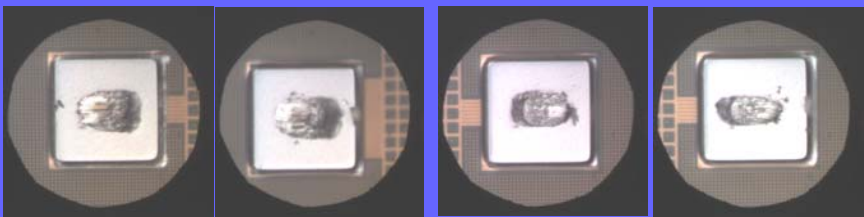
2D/3D Probe Tip Analysis

2D/3D Scrub Mark Analysis

Rapid Root Cause Analysis of Yield Loss

Rapid Full Wafer Punch-Thru Detection Via Spectral Analysis – “Go-No-Go”

Discovery

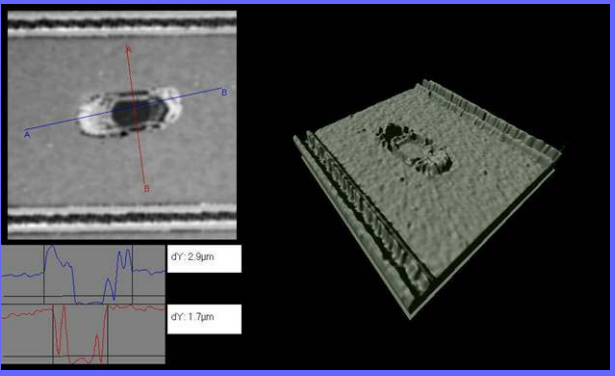


Exposed Copper Detected

Acceptable Pad Damage

- Reasons for exposed oxide
- => too many insertions
- => excessive overdrive
- => too thin aluminum
- => too soft aluminum

Root Cause Analysis

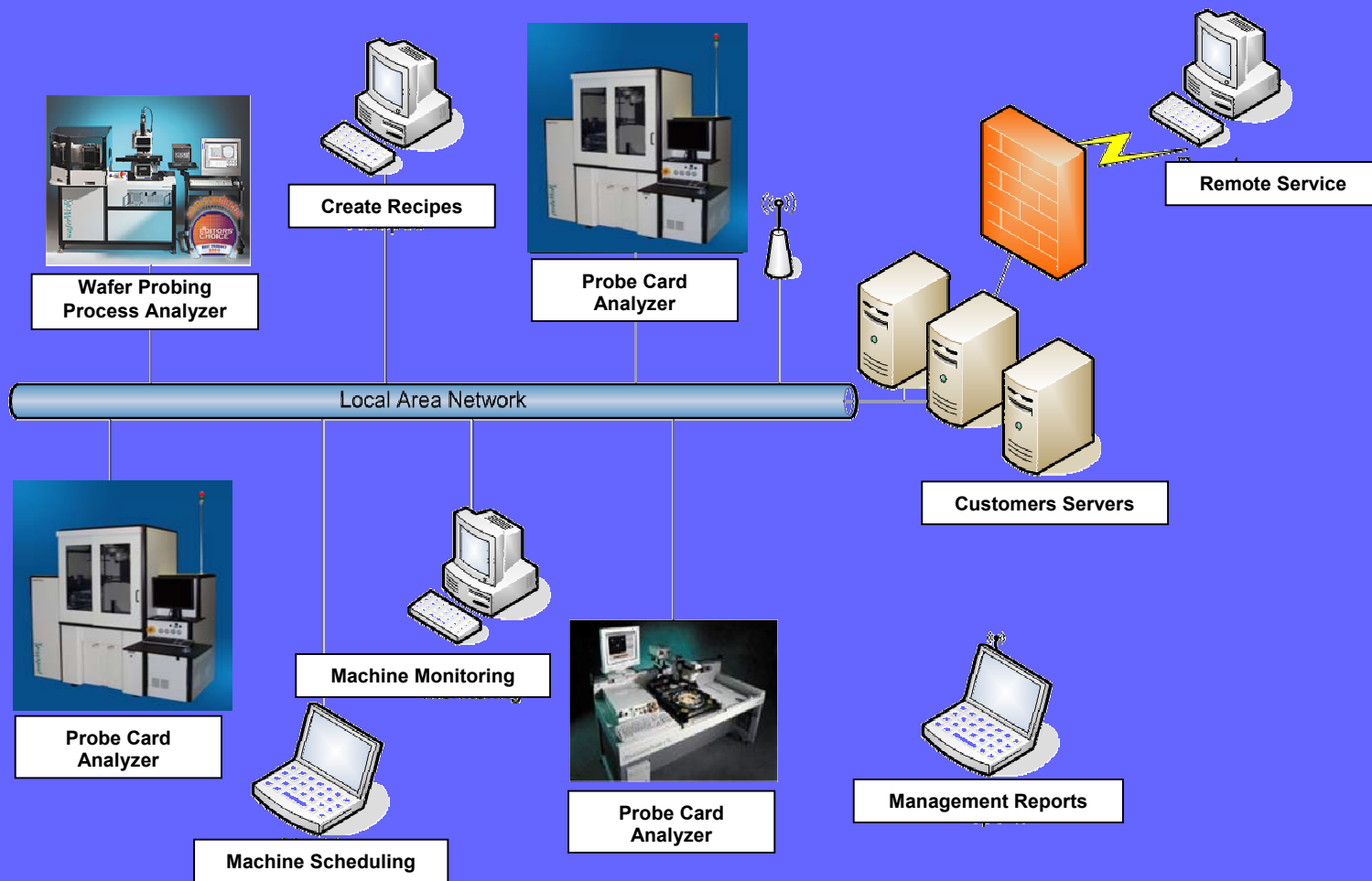


Automated and/or Manual 3D Scan Capability

Advanced Optical Analysis - Yield Loss
(Related to Wafer Fab or Wafer Test Process)

Closed Loop Metrology Enabled

All Data Centrally Located and Linked



Bridging the Gaps Between Advanced Optical Analysis & 3D Optical Comparative Metrology with Parametric Analysis

Problem

- **The Need to Rapidly Determine and Resolve the Causes of Yield Loss**

Solution

- **Advanced Scrub Mark Analysis (including pad punch-thru)**
- **Advanced Probe Tip Analysis**
- **Close the Gap Between PC Manufacturers and the Fabs Via CLM**

Result

- **Increased Wafer Test Yield!!!**

Solutions Require Close Working Relationships and Collaborations